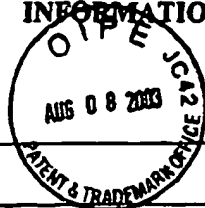


**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**



Attorney Docket Number	4641-59261
Application Number	09/881,445
Filing Date	June 13, 2001
First Named Inventor	Ushio
Art Unit	2818
Examiner Name	Not yet assigned

**U.S. PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
MS		4,645,349	Feb. 24, 1987	Tabata
MS		4,744,660	May 17, 1988	Noguchi <i>et al.</i>
MS		5,696, 583	Dec. 9, 1997	Yoon
MS		5,893,796	Apr. 13, 1999	Birang <i>et al.</i>
MS		5,964,643	Oct. 12, 1999	Birang <i>et al.</i>
MS		6,045,439	Apr. 4, 2000	Birang <i>et al.</i>
MS		6,280,290 B1	Aug. 28, 2001	Birang <i>et al.</i>
MS		US2001/0036805 A1	Nov. 1, 2001	Birang <i>et al.</i>
MSB		6,537,133 B1	Mar. 25, 2003	Birang <i>et al.</i>

**FOREIGN PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
MS		56-153207 /	Nov. 27, 1981	Japan (w/English abstract)
MS		60-305 /	Jan. 5, 1985	Japan (w/English translation of relevant part)
MS		61-76904 /	April 19, 1986	Japan (corresponds to US 4,645,349)
MS		61-235708 /	Oct. 21, 1986	Japan (corresponds to US 4,744,660)
MS		63-50703 /	March 3, 1988	Japan (w/English translation of relevant part)
MS		64-57107 /	March 3, 1989	Japan (w/English translation of relevant part)
MS		6-147838 /	May 27, 1994	Japan (w/English translation)









EXAMINER  
SIGNATURE:

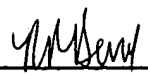
*MSB*

DATE  
CONSIDERED:

10-27-04

\* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> 		Attorney Docket Number		4641-59261
		Application Number		09/881,445
		Filing Date		June 13, 2001
		First Named Inventor		Ushio
		Art Unit		2818
		Examiner Name		Not yet assigned
		6-252113	Sept. 9, 1994	Japan (w/English translation)
		8-145631	June 7, 1996	Japan (corresponds to US 5,696,583)
		9-7985	Jan. 10, 1997	Japan (corresponds to US 6,537,133)
		EP 0824995 A1	Feb. 25, 1998	EPC
		EP 0738561 B1	Jan. 23, 2002	EPC
<b>Examiner's Initials*</b>	<b>Cite No. (optional)</b>	<b>OTHER DOCUMENTS</b>		
		Ushio <i>et al.</i> , "In-situ monitoring of CMP process utilizing 0-order spectrometry," <i>CMP-IMC Conference</i> , pp. 23-29, Feb. 11-12, 1999		
		Ushio <i>et al.</i> , "In-situ monitoring of CMP process utilizing 0-order spectrometry," <i>IMIC Journal on CMP</i> , Vol. 1, No. 1, Fall, 1999		

EXAMINER SIGNATURE: 	DATE CONSIDERED: 10-27-04
<p>* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>	



# INFORMATION DISCLOSURE STATEMENT

BY APPLICANT

Docket: 4641-59261

App: 09/881,445

Applicant: Ushio et al.

Filed: June 13, 2001

Art Unit: 2818

## U.S. PATENT DOCUMENTS

Init.*		Number	Date	Name	Class	Sub	Filed

## FOREIGN PATENT DOCUMENTS

		Number	Date	Country	Class	Sub	
<i>MM</i>		JP63-050703	3/3/98	Japan With English Abstract	—	—	
<i>MM</i>		JP64-057107	3/3/89	Japan With English Abstract	—	—	
<i>MM</i>		JP06-252113	9/9/94	Japan With English Abstract	—	—	

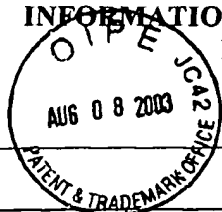
## OTHER DOCUMENTS


EXAMINER: *MM*

DATE *10-27-04*

\*Examiner: Initial if considered, whether or not in conformance with MPEP 609; draw line through cite if not in conformance and not considered. Send copy.

**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**



Attorney Docket Number	4641-59261
Application Number	09/881,445
Filing Date	June 13, 2001
First Named Inventor	Ushio
Art Unit	2818
Examiner Name	Not yet assigned

**U.S. PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
<i>MM</i>		4,645,349	Feb. 24, 1987	Tabata
<i>MM</i>		4,744,660	May 17, 1988	Noguchi <i>et al.</i>
<i>MM</i>		5,696, 583	Dec. 9, 1997	Yoon
<i>MM</i>		5,893,796	Apr. 13, 1999	Birang <i>et al.</i>
<i>MM</i>		5,964,643	Oct. 12, 1999	Birang <i>et al.</i>
<i>MM</i>		6,045,439	Apr. 4, 2000	Birang <i>et al.</i>
<i>MM</i>		6,280,290 B1	Aug. 28, 2001	Birang <i>et al.</i>
<i>MM</i>		US2001/0036805 A1	Nov. 1, 2001	Birang <i>et al.</i>
<i>MM</i>		6,537,133 B1	Mar. 25, 2003	Birang <i>et al.</i>

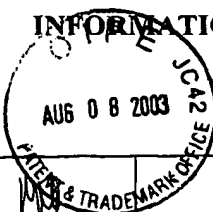







**FOREIGN PATENT DOCUMENTS**

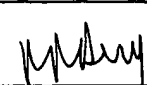
Examiner's Initials*	Cite No. (optional)	Number	Date	Country
<i>MM</i>		56-153207 /	Nov. 27, 1981	Japan (w/English abstract)
<i>MM</i>		60-305 /	Jan. 5, 1985	Japan (w/English translation of relevant part)
<i>MM</i>		61-76904 /	April 19, 1986	Japan (corresponds to US 4,645,349)
<i>MM</i>		61-235708 /	Oct. 21, 1986	Japan (corresponds to US 4,744,660)
<i>MM</i>		63-50703 /	March 3, 1988	Japan (w/English translation of relevant part)
<i>MM</i>		64-57107 /	March 3, 1989	Japan (w/English translation of relevant part)
<i>MM</i>		6-147838 /	May 27, 1994	Japan (w/English translation)


EXAMINER  
SIGNATURE: *YMM*

DATE  
CONSIDERED: 10-27-04

\* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> 		<b>Attorney Docket Number</b>		4641-59261
		<b>Application Number</b>		09/881,445
		<b>Filing Date</b>		June 13, 2001
		<b>First Named Inventor</b>		Ushio
		<b>Art Unit</b>		2818
		<b>Examiner Name</b>		Not yet assigned
		6-252113	Sept. 9, 1994	Japan (w/English translation)
		8-145631	June 7, 1996	Japan (corresponds to US 5,696,583)
		9-7985	Jan. 10, 1997	Japan (corresponds to US 6,537,133)
		EP 0824995 A1	Feb. 25, 1998	EPC
		EP 0738561 B1	Jan. 23, 2002	EPC
<b>Examiner's Initials*</b>	<b>Cite No. (optional)</b>	<b>OTHER DOCUMENTS</b>		
		Ushio <i>et al.</i> , "In-situ monitoring of CMP process utilizing 0-order spectrometry," <i>CMP-IMC Conference</i> , pp. 23-29, Feb. 11-12, 1999		
		Ushio <i>et al.</i> , "In-situ monitoring of CMP process utilizing 0-order spectrometry," <i>IMIC Journal on CMP</i> , Vol. 1, No. 1, Fall, 1999		

<b>EXAMINER SIGNATURE:</b> 	<b>DATE CONSIDERED:</b> 10-27-04
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.	

<b>INFORMATION DISCLOSURE STATEMENT</b>  <b>BY APPLICANT</b>				Docket: 4641-59261		App: (Unknown)	
				Applicant: Ushio et al.			
				Filed: June 13, 2001		Art Unit: (Unknown)	
<b>U.S. PATENT DOCUMENTS</b>							
Init.*		Number	Date	Name	Class	Sub	Filed
<i>MD</i>		6,102,775	8/15/00	Ushio et al.			31000 U.S. PRO 09/881445  06/13/01
<b>FOREIGN PATENT DOCUMENTS</b>							
		Number	Date	Country	Class	Sub	
		10311708	24.11.98	Japan (English Abstract Only)			
<b>OTHER DOCUMENTS</b>							
EXAMINER: <i>MD</i>				DATE: <i>10-27-04</i>			
*Examiner: Initial if considered, whether or not in conformance with MPEP 609; draw line through cite if not in conformance and not considered. Send copy.							